



MAKE	Axcelis
Model	GSD200E2 180keV
Process	High Current Implanter
Vintage (Year of Manufacture)	
Description	
Tool Status	unhooked
Software Version	6.4.4
CIM	Linked

Hardware Configuration

Main System	GSD200E2 Implanter	1	✓
SMIF System	Asyst LPT2200 smif Interface capability	1	✓
Handler System	Not applicable		
Process Chms	Not applicable		
Others (Pls specify if any)	Not applicable		

Hardware Configuration (Subfab / Auxilliary Units)

Cryo compressor	1	✓
Disk Chiller	1	✓

Configuration

	Axcelis GSD 200E2 Configuration
Vacuum system	
Cryo Compressor 1	CTI-8200 (P2)
Cryo Compressor 2	CTI-9700 (P3)
Beamline Cryo pump 1	OB 8 (P2)
Beamline Cryo pump 2	OB 10 (P3)
Process cryo P9	N
Source Pump	STPA2203C (P1)
AMU Turbo pump	N
Terminal Rough Pump	Ebara pump 40x20 (RP1)
Endstation Rough Pump	Ebara pump 40x20 (RP2)
Vacuum controller	HCIG
Endstation Info	
Cassette capability	Four cassette
wafer size	200mm
wafer notch alignment	Automatic Notch alignment capability with buffer cassette
Dummy wafer	Integrated "Dummy Wafer" Fill-In Capability
Wafer handling system	In-Air/In-Vacuum High Throughput Wafer Handling System
Particle Filter system	Class 1, UPLA Filtered Wafer Handling System
Implant angle capability	Two Axis Variable Implant Angle(+/- 11 deg in two axes) (Quad Implant Capability)
Process disk spindle	GSD series "Belt drive" Process disk (installed with active cooling and external close loop chiller)
Beam monitoring system	In Situ Beam Potential Monitor
	Real-time patented Dose Control
	Real-Time Beam Profiler(single dimension)
Process Disk	Silicon coated process disk (UHDsmall radius fence)
Process disk cooling interlock	Y
Asyst LPT2200 smif Interface capability	Y
Terminal Info	
Gas box Option	Modular gas box
	Four String Gas Box Options
	- 1 High Pressure String
	- 2 SDS string Hydride(Arsine and Phosphine)
	- 1 SDS string Flouride(Boron Trifluoride)
	- 3 Pressure Transducer on SDS string(per string) -- PSIA
	Mass Flow Controller :
	- 1 kit Unit 1660
	- 3 kits Unit 1662
Extraction PS	0 -90 KV
Extraction voltage monitor	Y
Vaporiser	Y
Ion Source	Eterna ELS(Extended Life Source)
Source bushing	Extended life bushing
	Source liner for Extended life bushing
N2 purge	Bypass Valve and Nitrogen Purge
Extraction Electrode	Extraction Electrode 34

Source injection kit	Y
AMU system	Triple Indexed Mass Analysis Magnet and Power Supply
Post Accel PS	0 -90 KV
Post accel electrode	N
Terminal transformer	Dry transformer
Bias aperture assy	Y
Flag faraday	Y
Charge control Technology	
Secondary Electron Flood Gun	PEF
Closed-Loop Cooling System Selection	
Cooling system	Single loop affinity chiller
General Info	
Control UPS	Y
Main Isolation transformer	Y
Abatement system	EGS237 Novapure (may sell separately)
Software version	6.4.4
Smoke detector	Y
Exhaust Flow switch	Y
Water leakage sensor	Y
Light Tower	Y
Real Time Particle Detection System	N
Advanced Automation Package	SUN SOLARIS Operator Workstation : Hard Drive,21" Monitor SECS I and SECS II Protocols, GEM Interface and Ethernet Ports